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Substitute for form 1449A/B/PTO INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use as many sheets as necessary)				Complete if Known	
				Application Number	10/780,667
				Filing Date	February 19, 2004
				First Named Inventor	Hironori Ibusuki
				Art Unit	1756
				Examiner Name	N/A Young
Sheet	1	of	1	Attorney Docket Number	SON-2920

U.S. PATENT DOCUMENTS					
Examiner Initials*	Cite No. ¹	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number-Kind Code ² (if known)			
CY	AA	5,831,272	11/3/98	Utsumi	
	AB				

FOREIGN PATENT DOCUMENTS						
Examiner Initials*	Cite No. ¹	Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ⁶
		Country Code ³ -Number ⁴ -Kind Code ⁵ (if known)				
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NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), data, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
	CA	EPL: Electron beam Proximity Lithography, "Projection Exposure with Variable Axis Immersion Lenses: A High Throughput Electron Beam Approach to Suboptical Lithography" H.C. Pfeiffer, Jpn. J. Appl. Phys. Vol. 34 (1995) pp. 6658-6662	
	CB	LEELP: Low Energy Electron beam Proximity Projection Lithography, "Characterization of a Process Development Tool for Ion Projection Lithography, Hans Leesechner, et al, J. Vac. Sci. Technol. B19, (2001)	
	CC	Complete copies have not been provided.	
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Examiner Signature	/Christopher Young/ (02/26/2007)	Date Considered	02/26/2007
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